

FIG. 1A

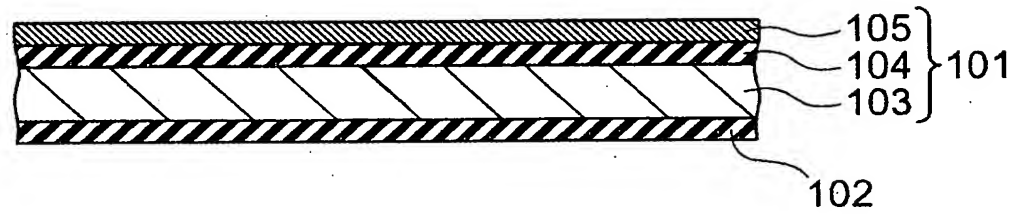


FIG. 1B

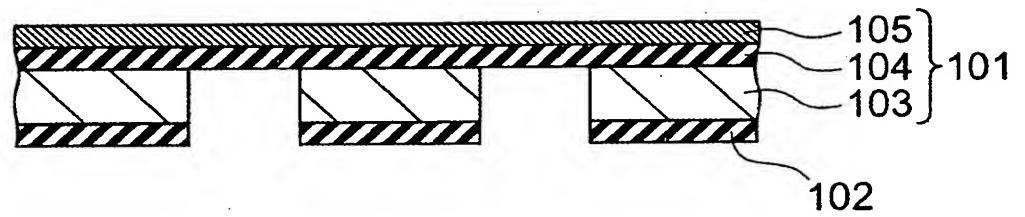


FIG. 1C

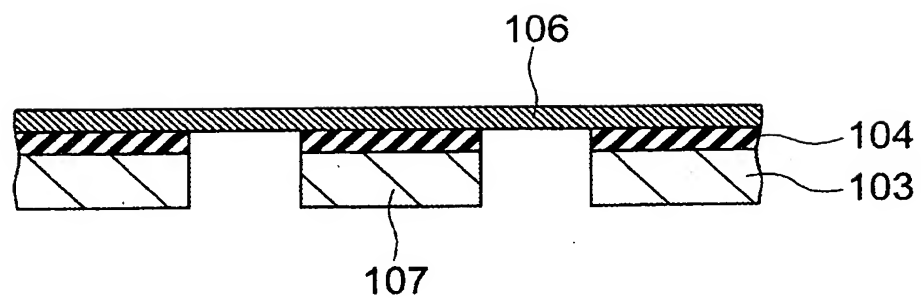


FIG. 1D

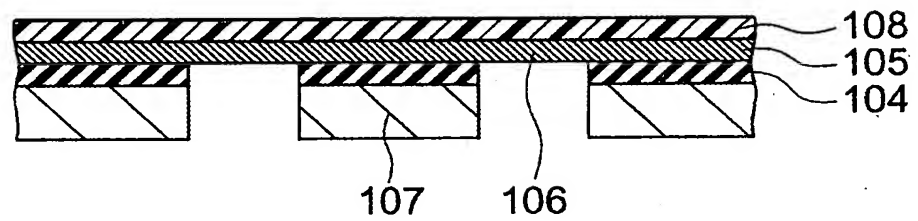


FIG. 1E

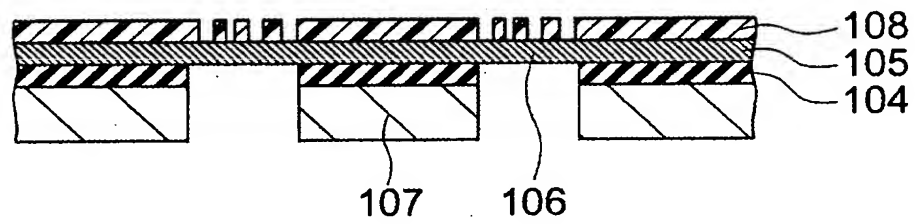


FIG. 1F

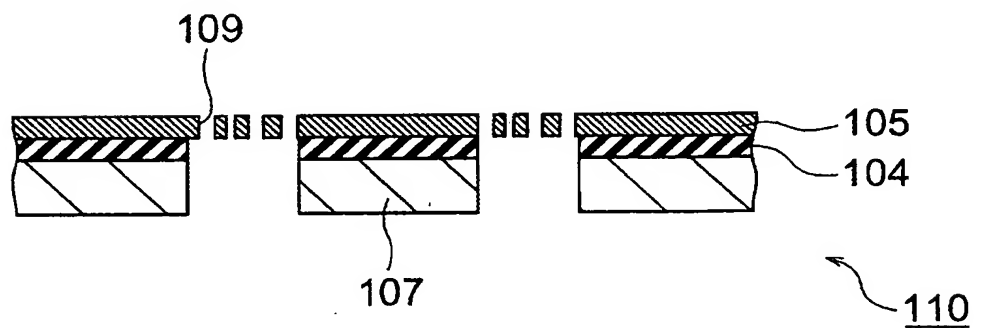


FIG. 2A

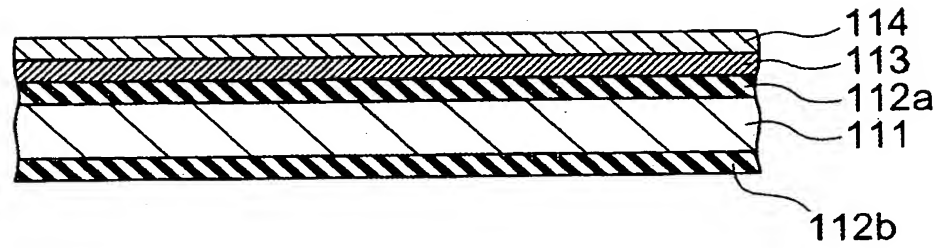


FIG. 2B

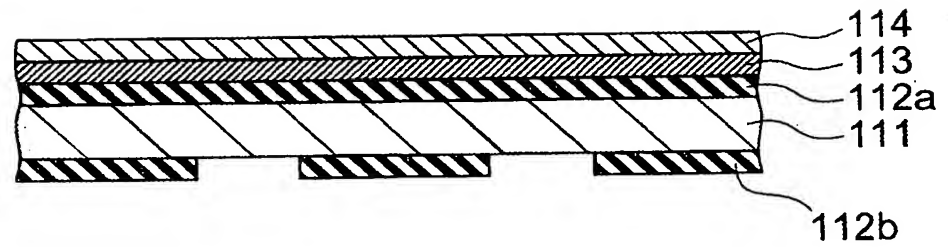


FIG. 2C

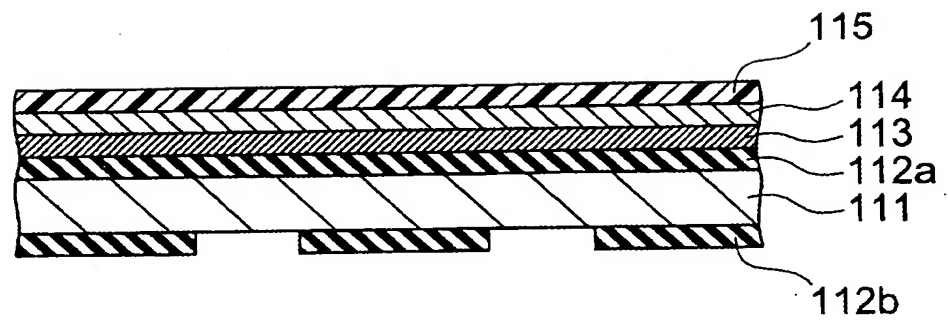


FIG. 2D

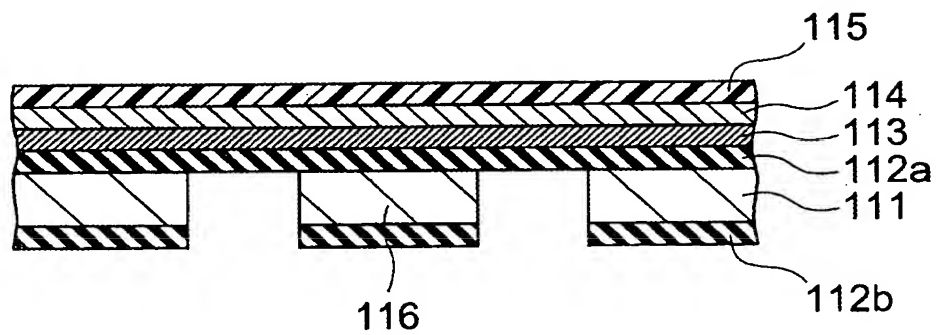


FIG. 2E

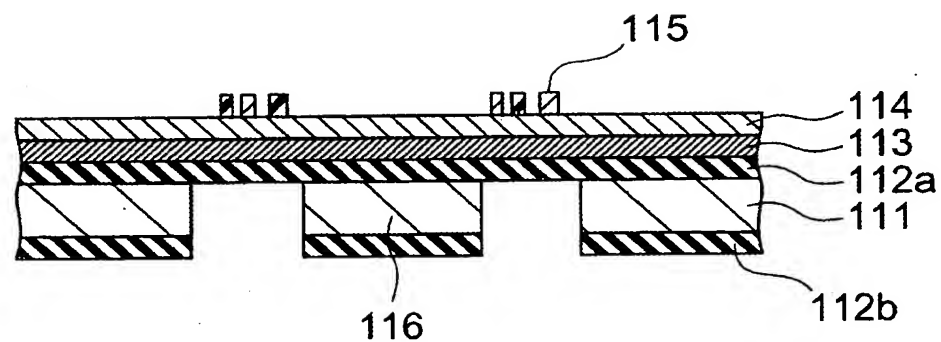


FIG. 2F

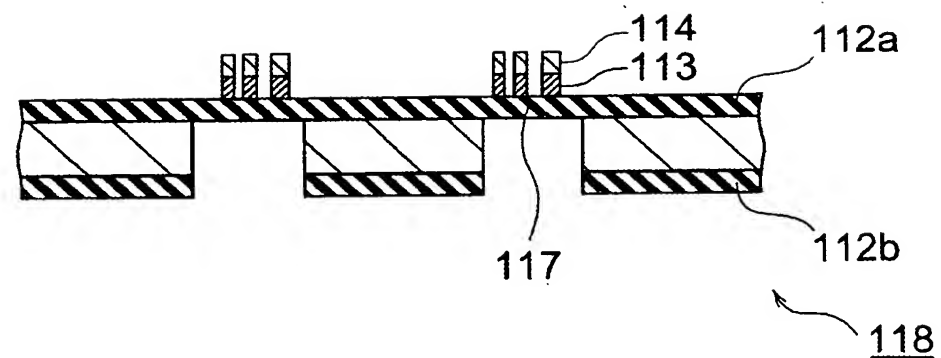


FIG. 3

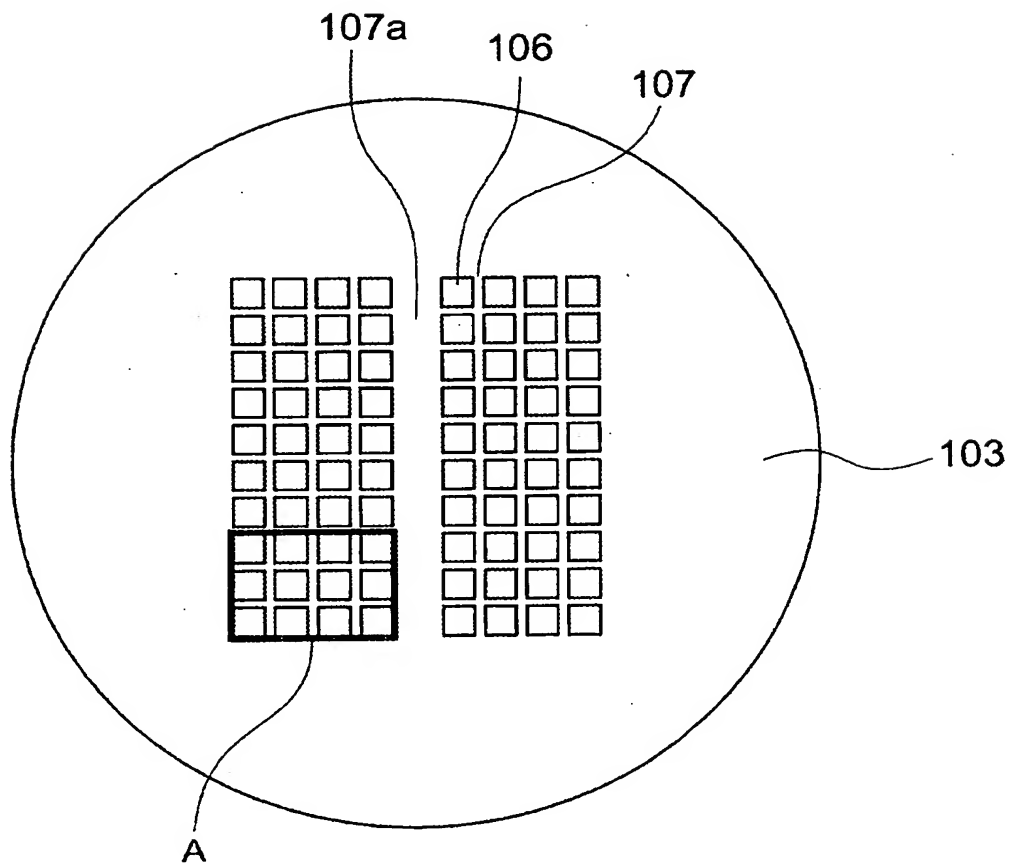


FIG. 4

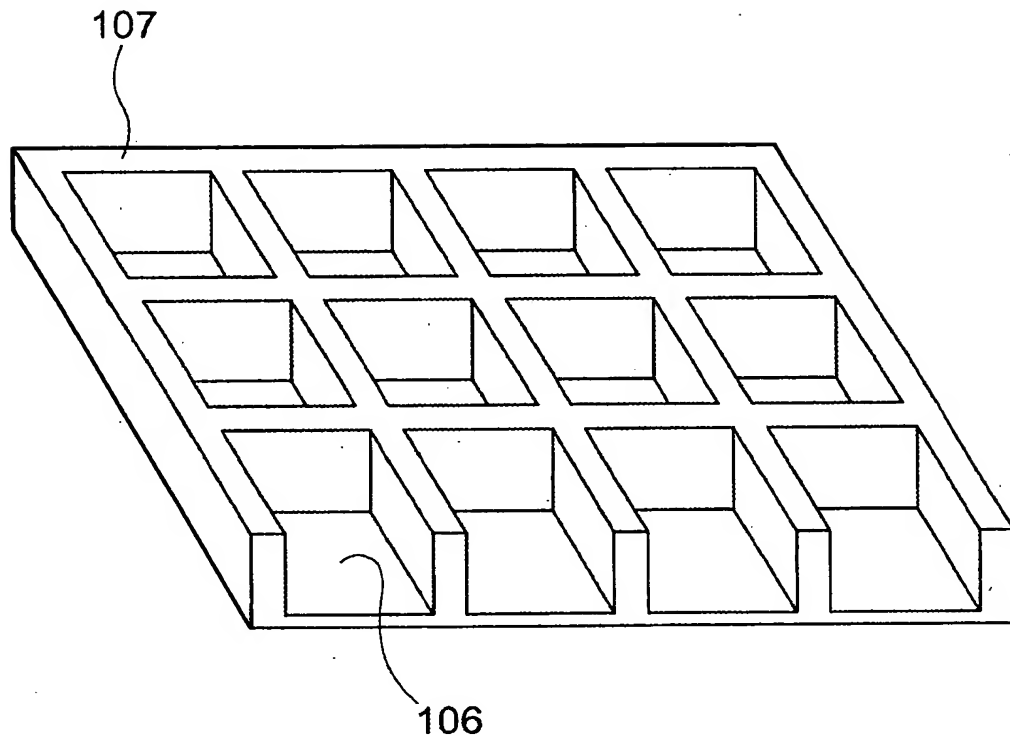


FIG. 5

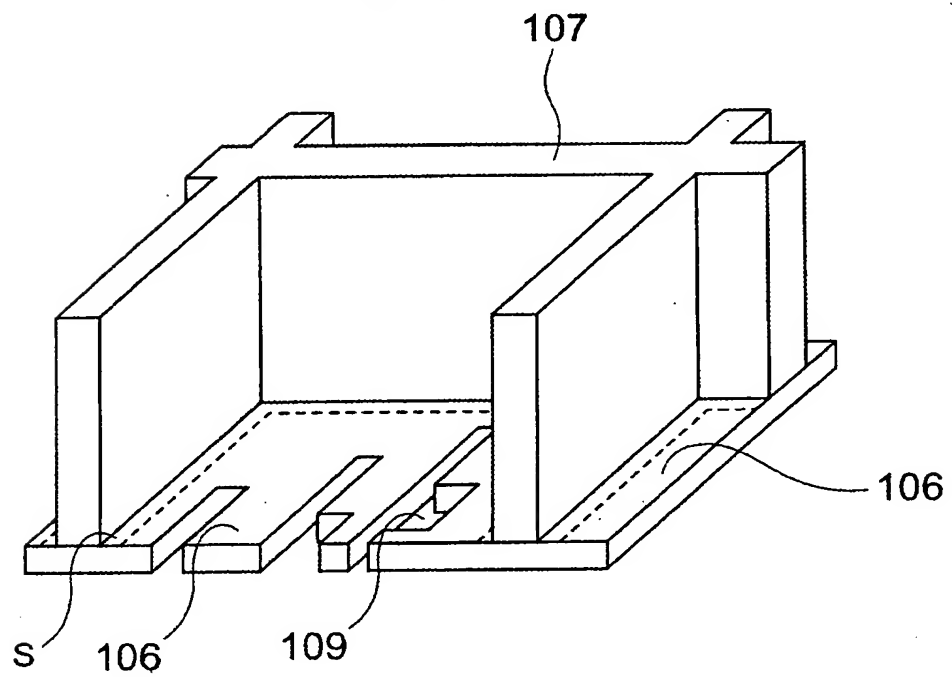


FIG. 6A

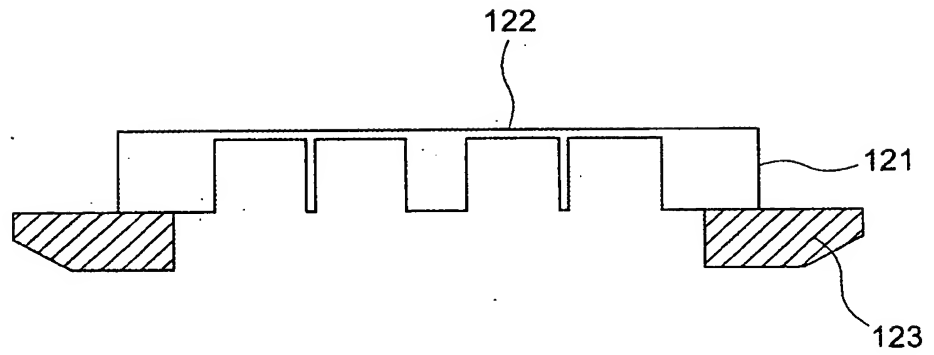


FIG. 6B

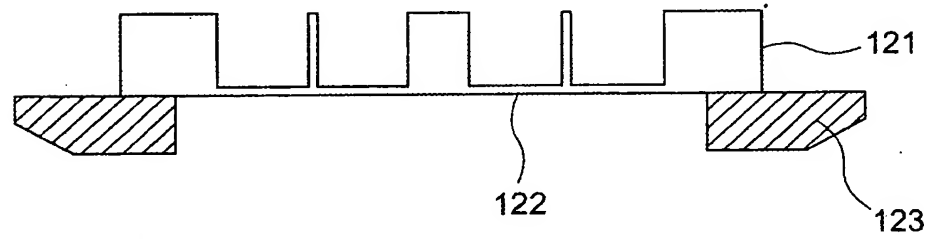


FIG. 7

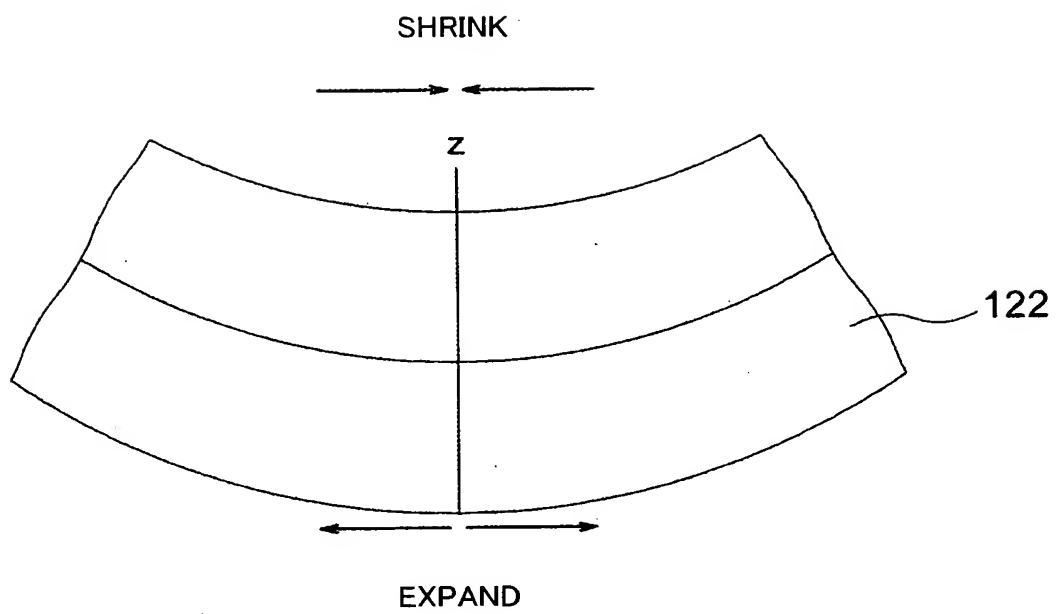


FIG. 8A

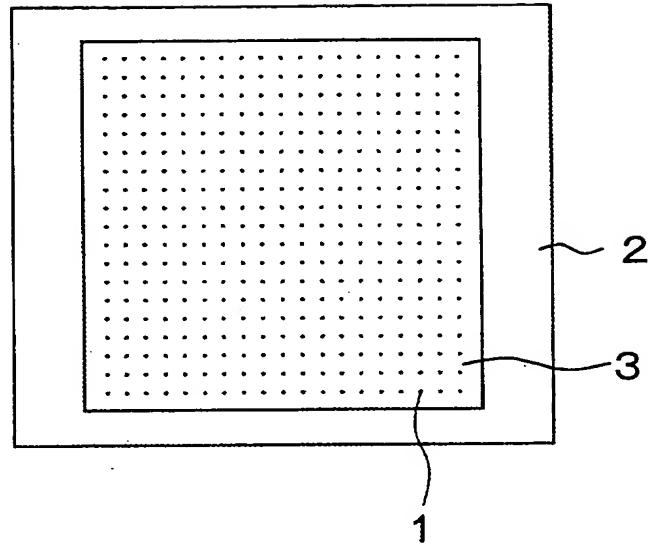


FIG. 8B

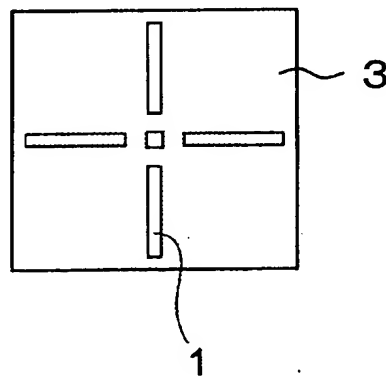


FIG. 9

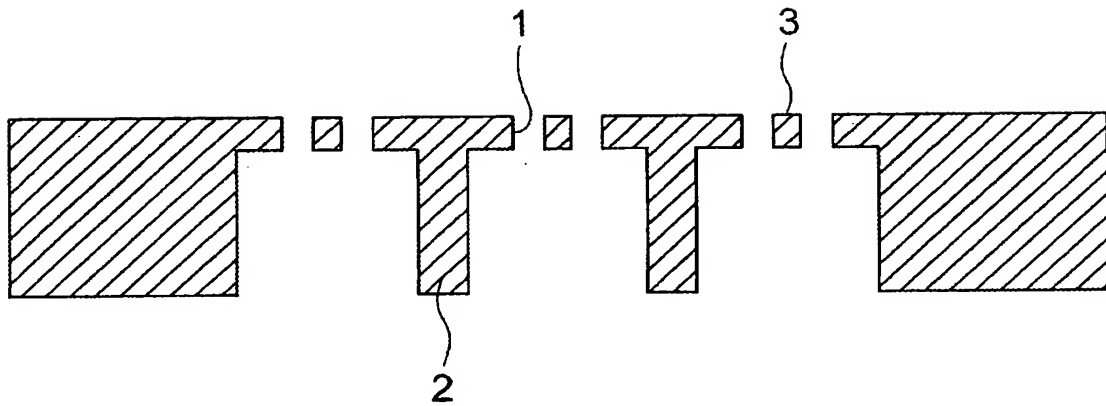


FIG. 10

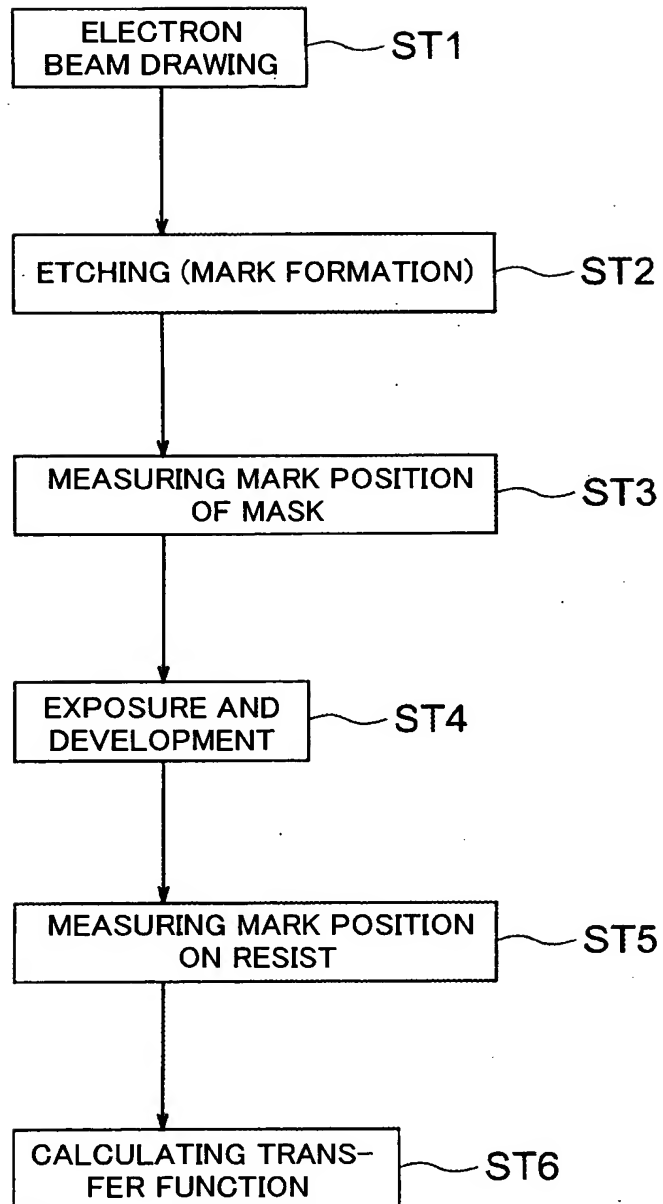


FIG. 11A

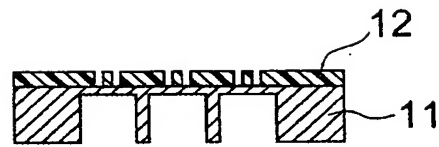


FIG. 11B

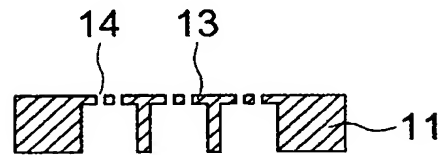


FIG. 11C



FIG. 11D



FIG. 12

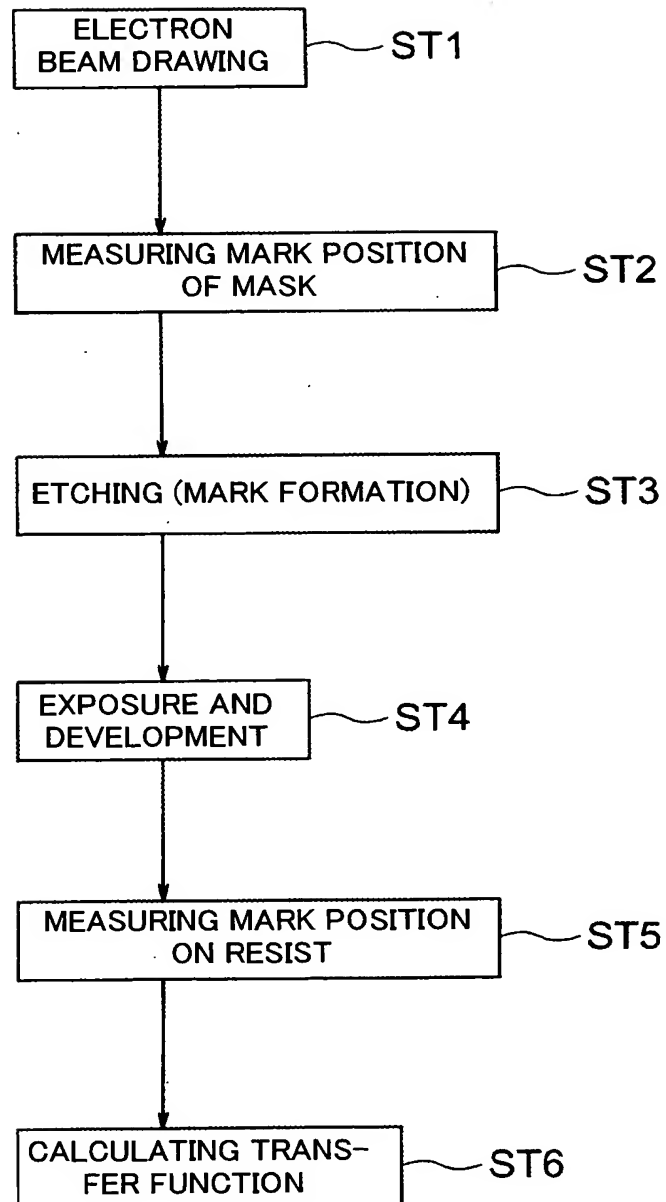


FIG. 13A

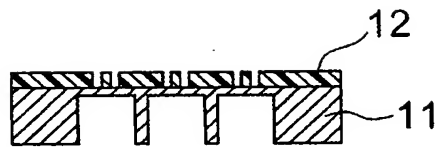


FIG. 13B

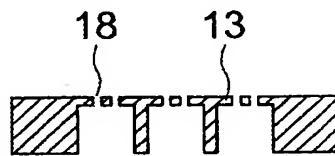


FIG. 13C



FIG. 13D



FIG. 14

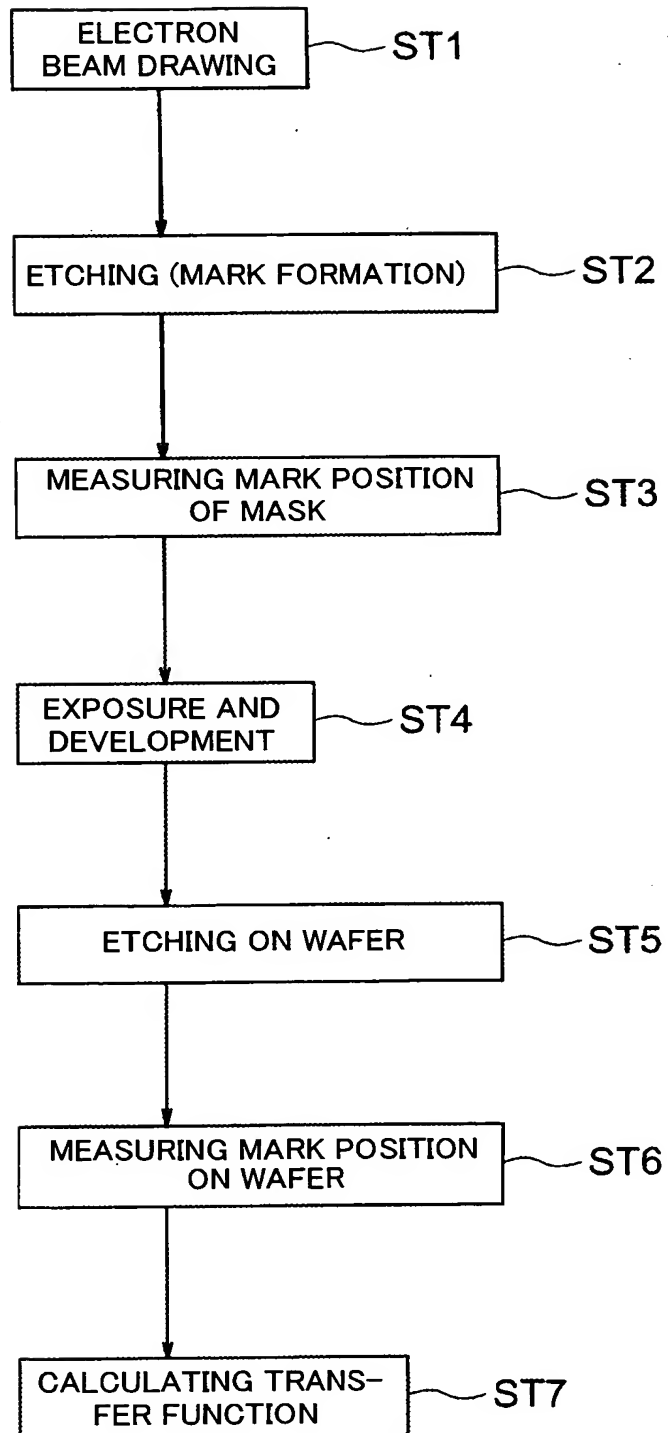


FIG. 15A

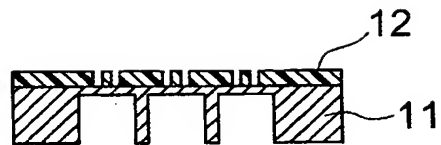


FIG. 15B

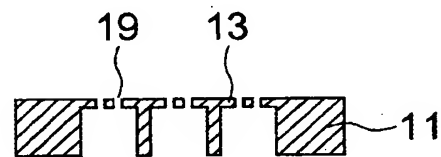


FIG. 15C

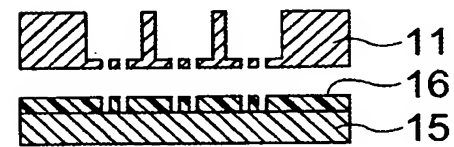


FIG. 15D

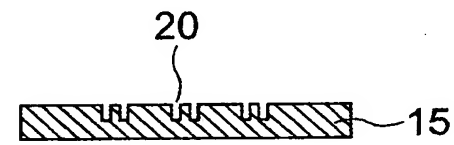


FIG. 16

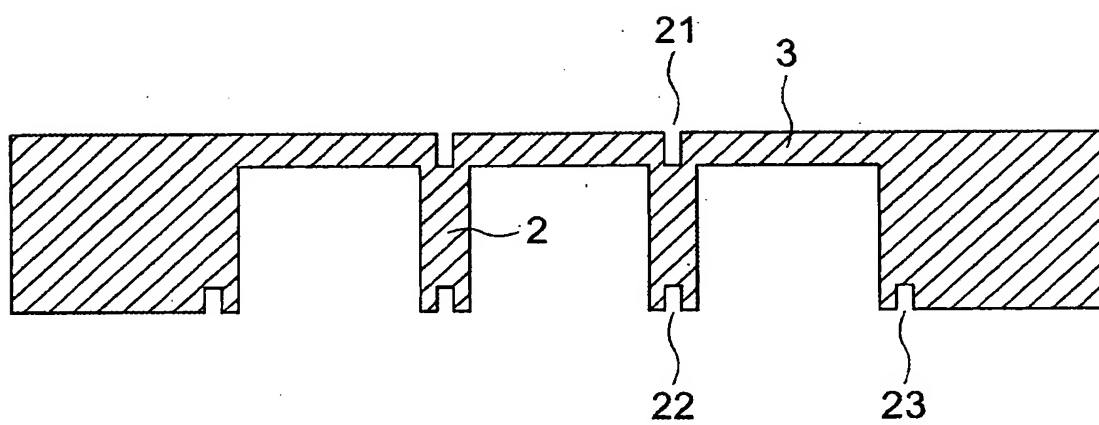


FIG. 17B

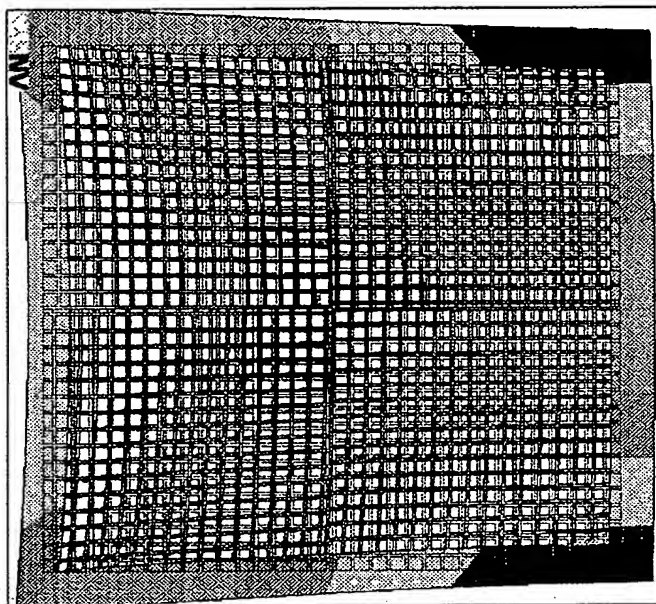


FIG. 17A

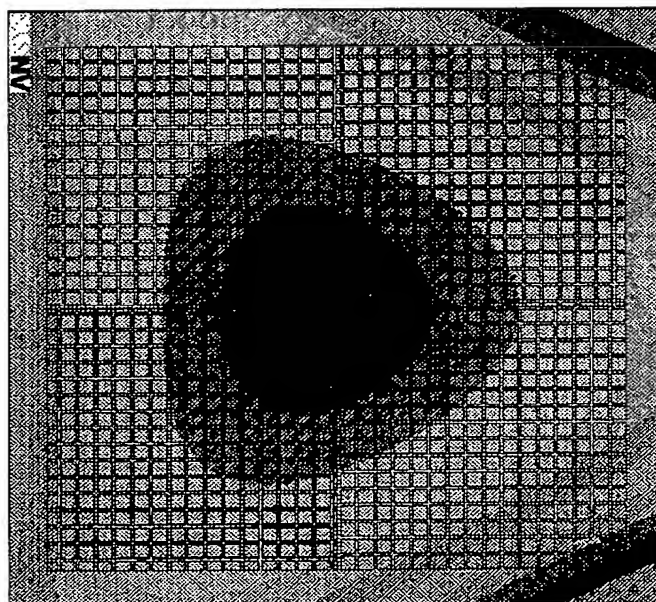


FIG. 18

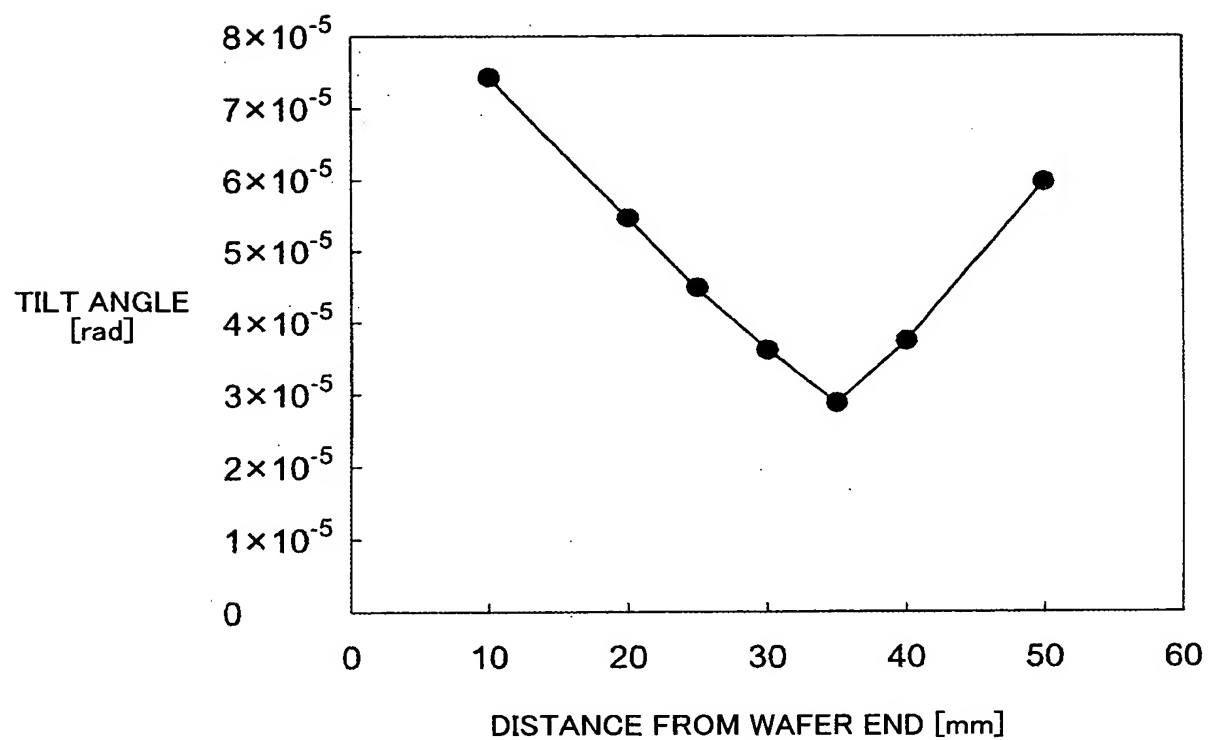


FIG. 19

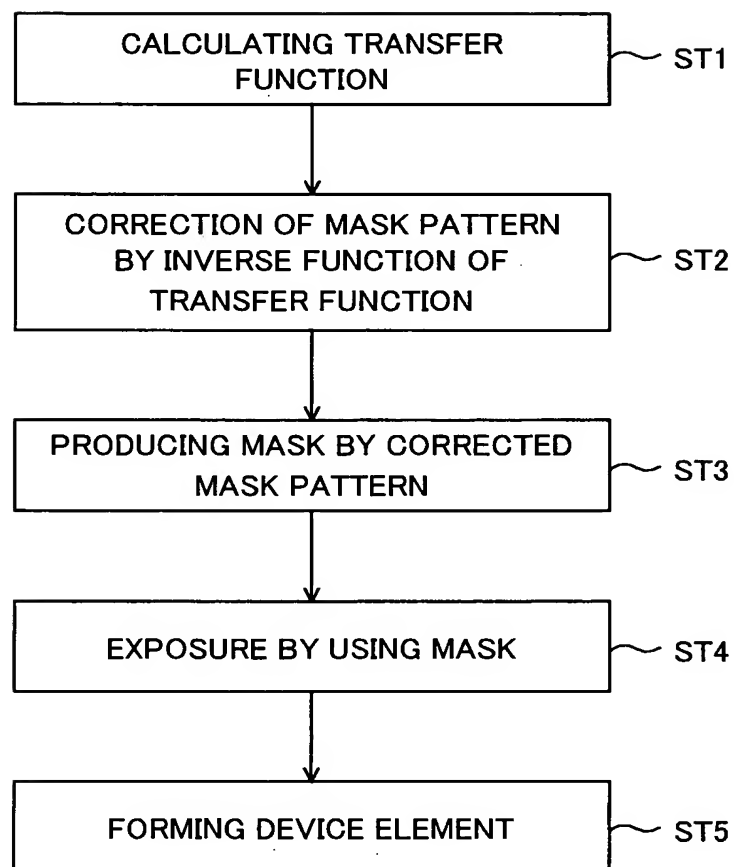


FIG. 20

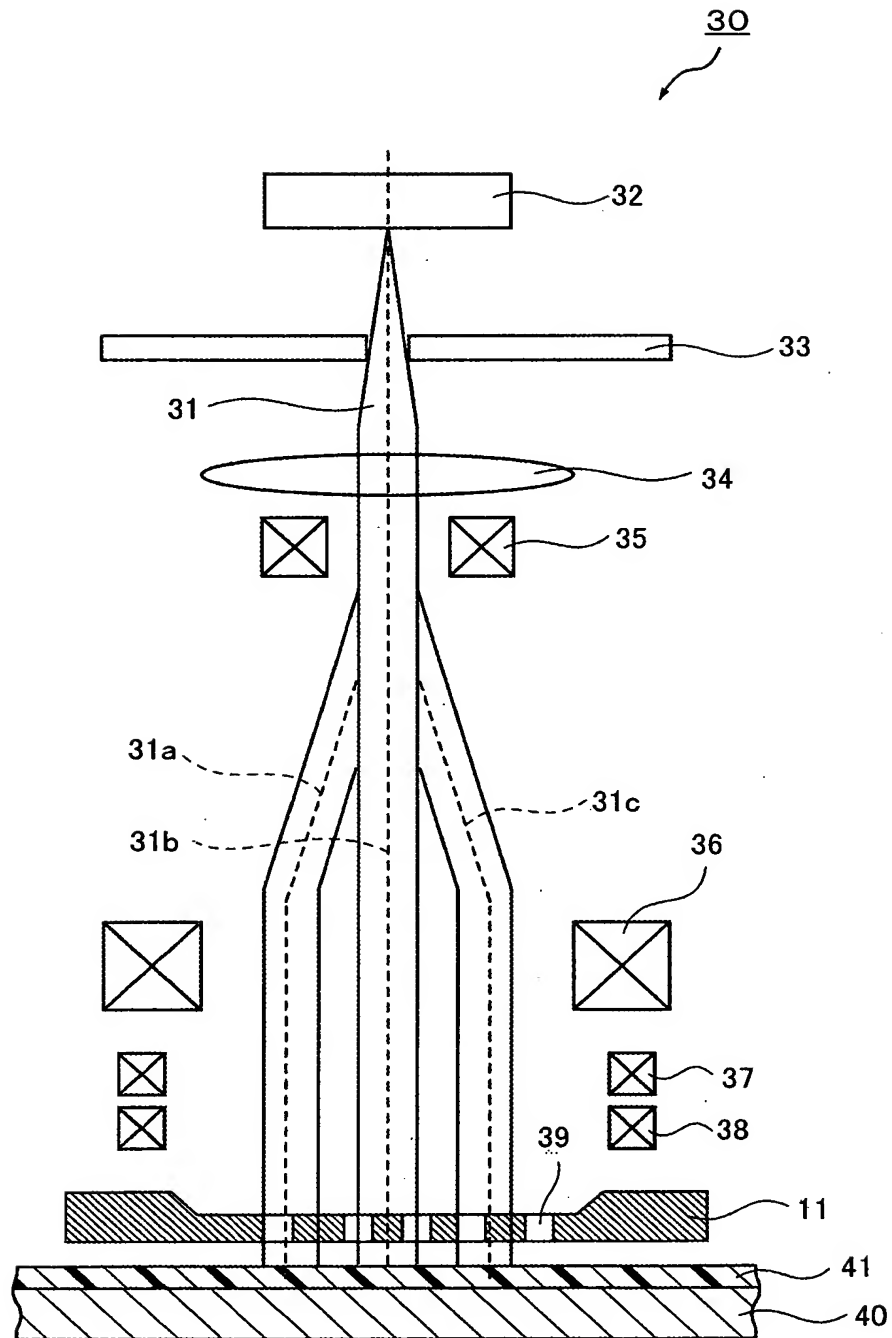
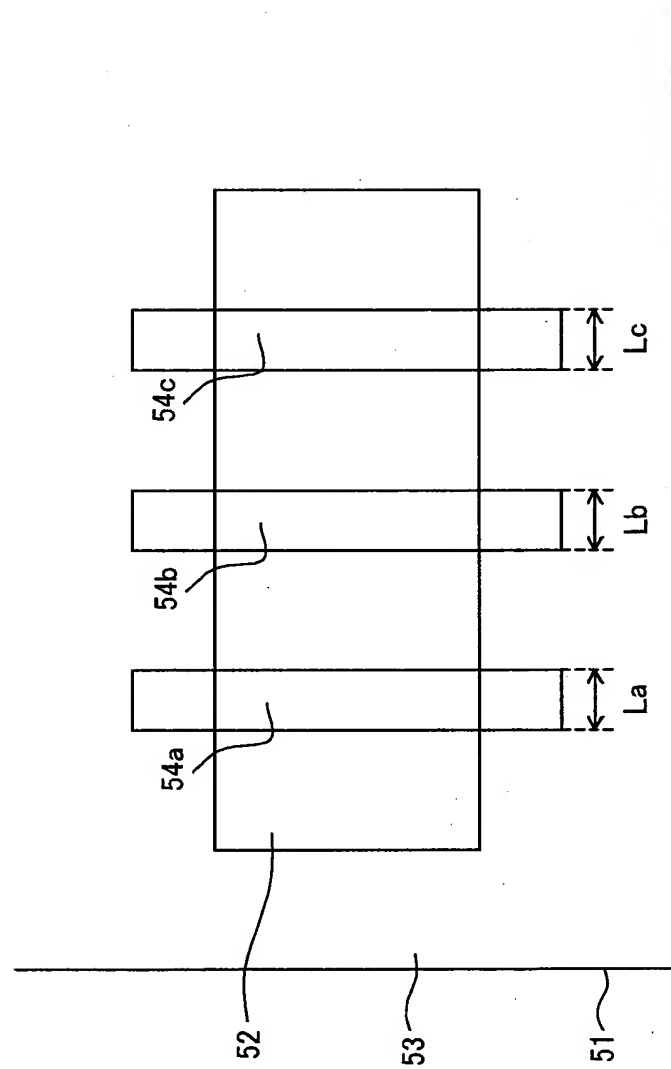


FIG. 21



Explanation of References

- 101... SOI wafer
- 102... silicon oxide film
- 5 103... silicon wafer
- 104... silicon oxide film
- 105... silicon layer
- 106... membrane
- 107 and 107a... beam
- 10 108... resist
- 109... hole
- 110... stencil mask
- 111... silicon wafer
- 112a, 112b... silicon nitride film
- 15 113... chrome layer
- 114... tungsten layer
- 115... resist
- 116... beam
- 117... membrane
- 20 118... membrane mask
- 121... mask
- 122... membrane
- 123... holding means
- 1... coordinate measuring instrument marks
- 25 2... beam
- 3... membrane



- 11... mask
- 12... resist
- 13... membrane
- 14... coordinate measuring instrument marks
- 5 15... wafer
- 16... resist
- 17, 18... mark
- 19... coordinate measuring instrument marks
- 20... mark
- 10 21... front surface side mark
- 22... back surface side mark
- 23... mark
- 30... exposure apparatus
- 31, 31a, 31b, 31c... electron beam
- 15 32... electron gun
- 33... aperture
- 34... condenser lens
- 35, 36... main deflector
- 37, 38... fine adjustment deflector
- 20 39... hole
- 40... wafer
- 41... resist
- 51... chip
- 52... active region
- 25 53... element separation region
- 54a, 54b, 54c... gate electrode